

Docket No.: 50090-334

L. Nelson  
#2/IDS  
10/29/01

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of

Masanobu IWASAKI, et al.

Serial No.:

Group Art Unit:

Filed: August 23, 2001

Examiner:

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING POLISHING  
SOLUTION, APPARATUS FOR AND METHOD OF POLISHING SEMICONDUCTOR  
SUBSTRATE AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

1c971 U.S. PTO  
09/934474  
08/23/01

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

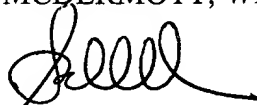
This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Serial No.:

Each non-English reference is accompanied by an English Abstract.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

A handwritten signature in black ink, appearing to read 'S. Becker', written over a horizontal line.

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